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2877

PATENT

IN THE UNITED STATES

PATENT AND TRADEMARK OFFICE

APPLICANT(S): Steven W. Meeks et al.  
APPLICATION NO.: 09/347,622 ✓  
FILING DATE: July 2, 1999  
TITLE: System for Simultaneously Measuring Thin Film Layers Thickness, Reflectivity, Roughness, Surface Profile and Magnetic Pattern  
EXAMINER: T. Nguyen  
GROUP ART UNIT: 2877  
ATTY. DKT. NO.: 20830-04304

RECEIVED  
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CERTIFICATE OF MAILING

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Dated: August 4, 2003

By:

Nathan S. Huynh, Reg. No.: 53,052

COMMISSIONER FOR PATENTS  
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STATUS REQUEST

SIR:

Our file for the subject application reveals that there has been no action on this application since the filing of the Information Disclosure Statement on July 14, 2003.

Please inform the undersigned, at the below stated address, of the status of this application.

Respectfully submitted,  
Steven W. Meeks et al..

Dated: August 4, 2003

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